

**INFORMATION DISCLOSURE
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Complete If Known

Application Number	10/081,818
Filing Date	February 20, 2002
First Named Inventor	Eldridge, Jerome
Group Art Unit	2818
Examiner Name	Ho, Tu-Tu

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Attorney Docket No: 1303.045US1

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Examiner Name	Ho, Tu-Tu

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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**
(Use as many sheets as necessary)**Complete If Known**

Application Number	10/081,818
Filing Date	February 20, 2002
First Named Inventor	Eldridge, Jerome
Group Art Unit	2818
Examiner Name	Ho, Tu-Tu
Attorney Docket No: 1303.045US1	

Sheet 7 of 8

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Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	T ²
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Group Art Unit	2818
Examiner Name	Ho, Tu-Tu

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